

# **AZIMUTHAL SCANNING OF A STRUCTURE FORMED ON A SEMICONDUCTOR WAFER**

## **ABSTRACT**

A structure formed on a semiconductor wafer is examined by directing an incident beam at the structure at an incidence angle and a azimuth angle. The incident beam is scanned over a range of azimuth angles to obtain an azimuthal scan. The cross polarization components of diffracted beams are measured during the azimuthal scan.